

# Studies on EWMA Control Chart in Presence of Autocorrelation

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**Abstract**— Control charts are used to monitor a production process. While using control charts, a standard assumption is that observations from the process at different time periods are independent random variable. However, the assumption of independency in observation is not always true rather they are dependent in many cases. For example, in many chemical process industries, the observation taken at different time points are often correlated due to the dynamic nature of the process. Sometimes, some process inherently produced data that are autocorrelated. The presence of autocorrelation in process observations can have a large impact on traditional control chart developed under independent assumptions. When there is significant autocorrelation in the process observation, it is not advisable to apply traditional control chart methodology without modification, as there is typical effect of the autocorrelation on the control limits. In this paper, an attempt has been made to study the effect of autocorrelation on *EWMA* chart which is used alternative to Shewhart Control Chart specially in detecting small shifts in the process. Both for positive and negative autocorrelation, the effect on *EWMA* control limits are studied and in order to account for the autocorrelation, control limits are adjusted with the modification of *EWMA* control chart parameters.

**Keywords**— Shewhart Control chart, *EWMA* Control chart, Independent, Dependent, Autocorrelation.

## 1. Introduction

A basic assumption in traditional application of Statistical Process Control (SPC) techniques is that the observations from the processes under investigation are normally and independently distributed. When these assumptions are satisfied, conventional control charts may be applied. However, the independence assumption is often violated in practice. The assumption of independent observations is not realistic for process of interest in many applications, because, the dynamics of the process produces autocorrelation in the process observation, such as in the chemical and pharmaceutical industries.

Hence, the study of the effect of autocorrelation is an interesting one and it is very much relevant to the industry. In discrete as well as in continuous production process data often shows some autocorrelation, or serial dependence. Autocorrelation is present in the data generated by most continuous and batch process operations since the value of the particular parameter under monitoring is dependent on the previous value of that parameter.

Continuous product manufacturing operations such as the manufacture of food, chemicals, paper and other wood products often exhibits serial correlation. This phenomenon can also be present in monthly series of survey quality data. It is more apparent for data collected with frequent sampling but can also be due to the dynamics of the process. For instance, observations from automated test and inspection procedures where every quality characteristic is measured on every unit in time order of production, or

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measurements of process variables from tanks, reactors and recycle streams in chemical processes are often highly correlated. Autocorrelation can also be evident in data arising from computer intrusion detection [Ye et al. [1] and Ye et al. [2]].

It is noteworthy to mention here that while dealing with autocorrelated data, so far there are two major approaches. These are:

- (i) One may adjust the control limits of existing SPC charts
- (ii) One may design residual based control charts.

In our present study, we will highlight some works on autocorrelated EWMA control charts based on Residual charts in section I. The study of effect of autocorrelation based on residual base EWMA chart has already been studied by the authors. Hence, in section II, the effect of autocorrelation on EWMA control limits are studied and in order to account for the autocorrelation, control limits are adjusted with the modification of EWMA control chart parameters both for positive as well as negative autocorrelation.

## 2. REVIEW OF PAST WORKS ON AUTOCORRELATED EWMA CONTROL CHARTS

Beneke et.al. [3] investigated spectral control charts based on periodogram analysis and compared them with the Shewhart  $\bar{X}$  and EWMA control charts. They recommended that the spectral control charts should be used along with existing control charts so that both shifts and cycles in the process mean can be detected.

Harvey and Fernandes [4] also Wisnowski and Keats [5] concluded that correlated count data can be modeled with a EWMA control chart.

Montgomery and Mastrangelo [6], emphasized that the use of EWMA is best for process observations that are positively autocorrelated at low lags and process mean that does not drift rapidly.

Harris and Ross [7] discussed the impact of autocorrelation on the performance of CUSUM

and EWMA charts, and showed that the average and median run lengths of these charts were sensitive to the presence of autocorrelation.

Wardell, Moskowitz and Plante [8] considered different control charts techniques in presence of data correlation and showed that the traditional EWMA chart is very good at detecting small shifts and perform well for large shifts when the autoregressive (AR) parameter is negative and Moving Average (MA) parameter is positive. Superville and Adamas [9] studied the performance analysis of CUSUM and EWMA control chart in detecting mean shift in AR processes. Tseng and Adams [10] generate in control ARLs with simulation for EWMA forecast errors. They compared the Shewhart, EWMA and CUSUM control chart. English [11] evaluated average run lengths of both  $\bar{X}$  and EWMA charts by using analytical and simulation technique and tabulated for various process disturbance scenarios due to autocorrelation. Van Brackle and Reynolds [12] considered the EWMA and CUSUM control chart for the process mean when the observations are from an AR (1) process with additional random error. The numerical result of ARL shows that correlation can have a sufficient effect on the properties of these charts.

Schmid and Schone [13] proved theoretically that the run length of the auto correlated process is larger than in the case of independent variables provided that all the auto covariances are greater than or equal to zero.

Lu and Reynolds [14] considered the problem of monitoring the mean of a process in which the observation can be modeled as an AR (1) process plus a random error. A EWMA control chart based on the residual from the forecast values of the model is evaluated using an integral equation method.

Lu and Reynolds [15] extended his work on [14] to study the problem detecting special cause which may produce change in the process mean and variance. Several types of control charts and combinations of control charts are evaluated by them for their ability to detect changes in the process mean and variance. Jiang, et.al. [16]



The smaller the values of  $\lambda$ , the more even are the successive weights. For instance, if  $\lambda = .1$  then the initial weight is .1 and the successive weights decrease by the factor .9; that is, the weights are .1, .09, .081, .073, .066, .059 and so on. On the other hand, if one choose, say  $\lambda = .4$ , then the successive weights are .4, .24, .144, .087, .052, ..... Since the successive weight  $\lambda (1 - \lambda)^{i-1}$ ,  $i = 1, 2, 3, \dots$ , can be written as

$$\lambda(1 - \lambda)^{i-1} = \bar{\lambda} e^{-\beta i}$$

Where

$$\bar{\lambda} = \frac{\lambda}{1 - \lambda}, \quad \beta = -\log(1 - \lambda)$$

We say that the successive older data values are "exponentially weighted". To compute the mean and variance of the  $W_t$ , recall that, when in control, the subgroup averages  $\bar{X}$ , are independent normal random variable each having mean  $\mu$  and variance  $\frac{\sigma^2}{n}$ . Therefore,

$$E[W_t] = \mu[\lambda + \lambda(1 - \lambda) + \lambda(1 - \lambda)^2 + \dots + \lambda(1 - \lambda)^{t-1} + (1 - \lambda)^t]$$

$$= \frac{\mu\lambda[1 - (1 - \lambda)^t]}{1 - (1 - \lambda)} + \mu(1 - \lambda)^t$$

$$= \mu_0$$

To determine the variance, we again use the equation

$$Var(W_t) = \frac{\sigma^2}{n} \{ \lambda^2 + [\lambda(1 - \lambda)]^2 + [\lambda(1 - \lambda)^2]^2 + \dots + [\lambda(1 - \lambda)^{t-1}]^2 \}$$

$$= \frac{\sigma^2}{n} \lambda^2 [1 + \beta + \beta^2 + \dots + \beta^{t-1}]$$

Where

$$\beta = (1 - \lambda)^2$$

$$= \frac{\sigma^2 \lambda^2 [1 - (1 - \lambda)^{2t}]}{n[1 - (1 - \lambda)^2]}$$

$$= \frac{\sigma^2 \lambda [1 - (1 - \lambda)^{2t}]}{n(2 - \lambda)}$$

Provided that the process has remained in control throughout, then for large values of  $t$ , the mean and variances reduced to:

$$E[W_t] = \mu_0 \quad \dots (3)$$

$$Var(W_t) \approx \frac{\sigma^2 \lambda}{n(2 - \lambda)} \text{ since } (1 - \lambda)^{2t} \approx 0 \quad \dots (4)$$

Thus, the upper and lower control limits for  $W_t$  are given by,

$$\left. \begin{aligned} UCL &= \mu_0 + 3\sigma \sqrt{\frac{\lambda}{n(2 - \lambda)}} \\ LCL &= \mu_0 - 3\sigma \sqrt{\frac{\lambda}{n(2 - \lambda)}} \end{aligned} \right\} \dots (5)$$

#### 4. MODEL DESCRIPTION:

LET US DEFINE THE PROCESS TO BE CONSIDERED BY

$$X_t = \mu + \xi_t \quad \dots (6)$$

Where  $\mu$  is constant and  $\xi_t$  satisfies

$$\xi_t = \rho_1 \xi_{t-1} + \rho_2 \xi_{t-2} + \dots + \rho_p \xi_{t-p} + \varepsilon_t$$

... (7)

Equation (7) is a p-th order autoregressive or AR (p) process.

If we now consider the autoregressive model of order 1, i.e., AR (1) model, which have many useful applications and simple as compared to higher order AR schemes, then we can expressed as

$$\xi_t = \rho_1 \varepsilon_{t-1} + \varepsilon_t$$

Where  $-1 < \rho_1 < 1$  and  $\rho_1$  is known as the coefficient of auto covariance and where  $\varepsilon_t$  is the stochastic disturbance term such that it satisfied the standard OLS assumptions, namely

$$E(\varepsilon_t) = 0$$

$$Var(\varepsilon_t) = \sigma_e^2$$

$$Cov(\varepsilon_t, \varepsilon_{t+s}) = 0; S \neq 0$$

In the *engineering literature*, an error term with the preceding properties is often called a *white noise error term* (Gujarati [28])

The process variance of model (6) is given by

$$Var(X_t) = \frac{\sigma_\varepsilon^2}{(1-\rho_1^2)} \quad \dots (8)$$

Further, for large n, the sample  $\bar{x}$  is the MLE of  $\mu$ . Hence,

$$E(\bar{x}_t) = \mu$$

$V(\bar{x}_t)$  is found out by Vasipoulos &

Stamboulis [29] as:

$$V(\bar{x}_t) = \frac{\sigma^2}{n} \left[ \frac{(1+\rho_1)}{(1-\rho_1)} - 2 \left\{ \frac{\rho_1(1-\rho_1^n)}{n(1-\rho_1)^2} \right\} \right] \quad \dots (9)$$

$$= \frac{\sigma^2}{n} \phi(\rho_1, n)$$

Where

$$\phi(\rho_1, n) = \left[ \frac{(1+\rho_1)}{(1-\rho_1)} - 2 \left\{ \frac{\rho_1(1-\rho_1^n)}{n(1-\rho_1)^2} \right\} \right] \quad \dots (10)$$

Therefore, the modified EWMA control limits for the discussed model would be

$$UCL = \mu_0 + 3\sigma \sqrt{\frac{r}{n(2-\lambda)}} \phi(\rho_1, n)$$

$$CL = \mu_0 \quad \dots (11)$$

$$LCL = \mu_0 - 3\sigma \sqrt{\frac{r}{n(2-\lambda)}} \phi(\rho_1, n)$$

Where  $\phi(\rho_1, n)$  is given in equation no. (10)

### 5. NUMERICAL ILLUSTRATIONS AND CONCLUSION

The specification of formalin product of a chemical factory (APL in Assam) is set up as  $37 \pm 0.5$ , by weight of Formaldehyde content. If the weight of formaldehyde gas in Formalin is below 36.5%, the

customers do not accept it and if the same is above 37.5%, it is not affordable to manufacturer so far its cost-benefit margin are concerned. The data for thirty days has been collected by taking 5 samples from the recorded data sheet from the chemical factory.

To detect the small change that may have occurred during the production time of the given Formalin data we construct EWMA control limits choosing various values of  $\lambda$  and control limit L. The calculated control limits are shown in Table 1 below-

TABLE 1. CALCULATION OF UPPER AND LOWER CONTROL LIMITS

SET-I			
$\lambda$	L	$UCL = \mu_0 + L\sigma \sqrt{\frac{\lambda}{2-\lambda}}$	$LCL = \mu_0 - L\sigma \sqrt{\frac{\lambda}{2-\lambda}}$
0.05	2.6	37.3951	36.6049
0.06	2.6	37.4339	36.5661
0.07	2.6	37.4699	36.5301
0.08	2.6	37.5037	36.4963
0.09	2.6	37.5356	36.4644
0.10	2.6	37.5661	36.4339
SET-II			
$\lambda$	L	$UCL = \mu_0 + L\sigma \sqrt{\frac{\lambda}{2-\lambda}}$	$LCL = \mu_0 - L\sigma \sqrt{\frac{\lambda}{2-\lambda}}$
0.05	2.8	37.4255	36.5745
0.06	2.8	37.4673	36.5327
0.07	2.8	37.5061	36.4939
0.08	2.8	37.5424	36.4576
0.09	2.8	37.5738	36.4232
0.10	2.8	37.6096	36.3904

From the set of calculated control limits it is found to meet the APL factory specification, the following values of  $\lambda$  and L i.e.  $\lambda = 0.08$  and L = 2.6 are suitable for constructing EWMA control limits which gives

$$UCL = 37 + 0.5037 = 37.50$$

$$CL = 37.00$$

$$LCL = 37 - 0.5037 = 36.50$$

Table 2 below gives the calculated EWMA control limits in presence of various values of positive as well as negative values of autocorrelation

Table 2. EWMA CONTROL LIMITS IN PRESENCE OF AUTOCORRELATION

$\rho_1$	$\lambda$	$\phi(\rho_1, n)$	L	UCL with autocorrelation	LCL with autocorrelation
0.1	0.8	1.17284	2.6	37.244	36.755
-0.1	0.8	0.8512	2.6	37.208	36.792
0.2	0.8	1.3750	2.6	37.264	36.735
-0.2	0.8	0.7222	2.6	37.191	36.808
0.3	0.8	1.6128	2.6	37.286	36.713
-0.3	0.8	0.6096	2.6	37.176	36.824
0.4	0.8	1.89344	2.6	37.310	36.689
-0.4	0.8	0.51104	2.6	37.161	36.838
0.5	0.8	2.225	2.6	37.336	36.663
-0.5	0.8	0.425	2.6	37.147	36.853

It is seen from the table that, the upper control limit has increases gradually as the positive autocorrelation coefficient increases and the upper control limits decreases as the negative autocorrelation coefficients decreases. Similarly,



the lower control limit decreases as the positive autocorrelation coefficient increases and the lower control limit increases as the negative autocorrelation coefficient increases. We may conclude that both the positive as well as negative autocorrelation have significant effect on the EWMA control limits.

To compensate the amount of autocorrelation, the user should adjust the control limits by choosing appropriate values of  $\lambda$  and L. For our above study, Table 3 shows the adjusted EWMA control limits for specific values of  $\lambda$  and L.

Table 3. ADJUSTED EWMA CONTROL LIMITS

$\rho_1$	$\lambda$	$\phi(\rho_1, n)$	L	UCL with autocorrelation	LCL with autocorrelation
0.1	0.30	1.17284	2.6	37.50	36.50
-0.1	0.35	0.8512	2.8	37.50	36.50
0.2	0.25	1.3750	2.7	37.50	36.50
-0.2	0.40	0.7222	2.75	37.50	36.50
0.3	0.20	1.6128	2.8	37.50	36.50
-0.3	0.50	0.6096	2.6	37.50	36.50
0.4	0.20	1.89344	2.6	37.50	36.50
-0.4	0.52	0.51104	2.8	37.50	36.50
0.5	0.15	2.225	2.8	37.50	36.50
-0.5	0.60	0.425	2.8	37.50	36.50

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